



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No. 10/720,724

Filing Date: November 24, 2003

Applicant: Mitsuro ATOBE

Group Art Unit: 1763

Examiner: Rakesh K. Dhingra

Title: MASK VAPOR DEPOSITION METHOD, MASK VAPOR DEPOSITION SYSTEM, MASK, PROCESS FOR MANUFACTURING MASK, APPARATUS FOR MANUFACTURING DISPLAY PANEL, DISPLAY PANEL, AND ELECTRONIC DEVICE

Attorney Docket: 9319K-000606

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

AMENDMENT

Sir:

In response to the Office Action mailed March 12, 2007, please amend the application as follows and consider the remarks set forth below.

Remarks begin on page 2 of this paper.